



566.41191X00

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Y. KURATA, et al.  
Application No.: 10/049,672  
Filed: February 15, 2002  
For: POLISHING MEDIUM FOR CHEMICAL-MECHANICAL  
POLISHING, AND METHOD OF POLISHING  
Examiner: 1765  
Group: D. Deo

**AMENDMENT**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

July 8, 2004

Sir:

In response to the Office Action mailed January 8, 2004, please amend the above-identified application as listed in the following, and as set forth on the following pages:

Amendments to the Claims; and

Remarks are included following the amendments.